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OMB No. 0651-0011 (12/31/86)  
Sheet 1 of 3

<b>Form PTO-1449</b> <b>U.S. Department of Commerce</b> <b>Patent &amp; Trademark Office</b>  <b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)	<b>Atty. Docket No.</b> RD-28,645	<b>Serial No.</b> Unassigned
	<b>Applicant(s):</b> Radislav A. Potyrailo James N. Cawse	
	<b>Filing Date</b> Herewith	<b>Group</b> Unassigned

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Examiner * Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
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Examiner * Initial	Document Number	Date	Country	Class	Subclass	Translation Yes No
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W	6,168,914 B1	1/2/2001	Campbell et al.	435	4	12/18/1998
W	6,200,737	3/13/2001	Walt et al.	430	320	8/24/1995

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
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